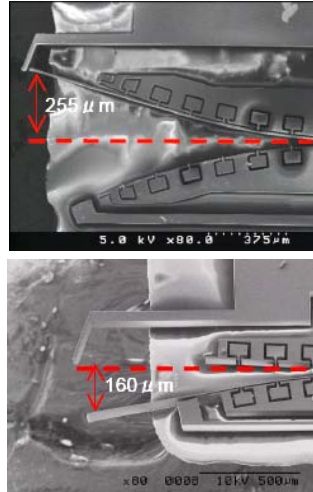
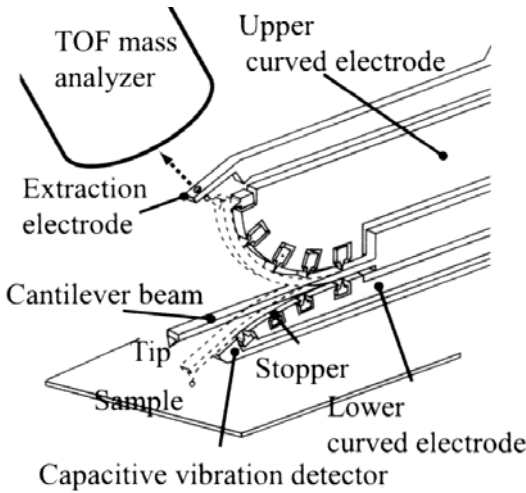
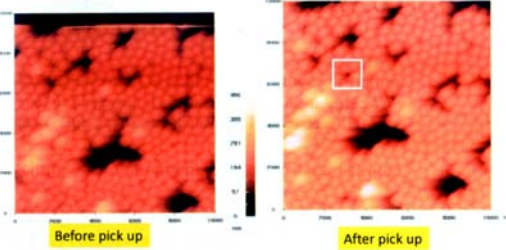


走査プローブ顕微鏡(SPM)プローブ

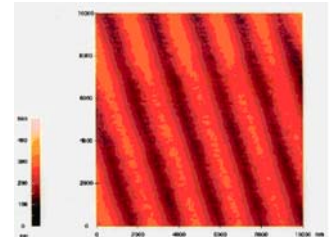
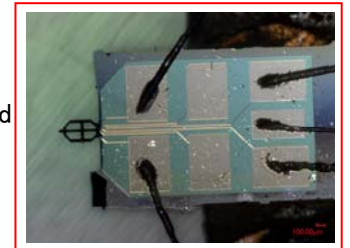
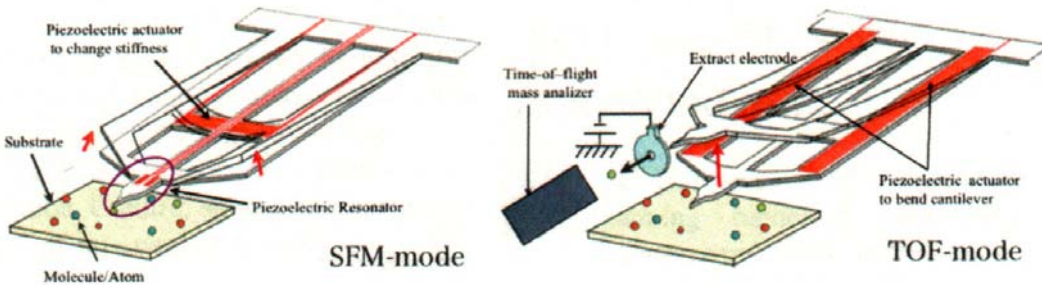


•Latex beads with 400 nm are spread on Si wafer



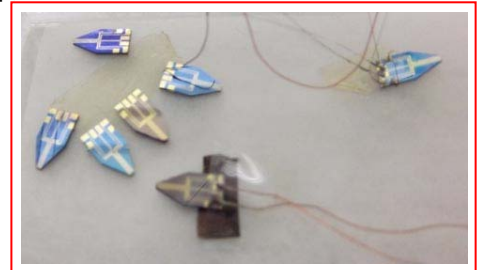
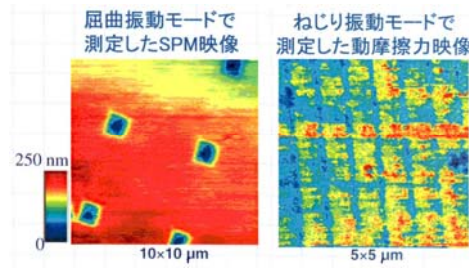
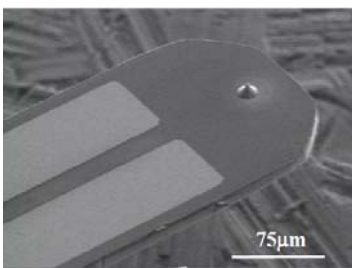
静電駆動飛行時間質量分析機能付 AFM プローブ

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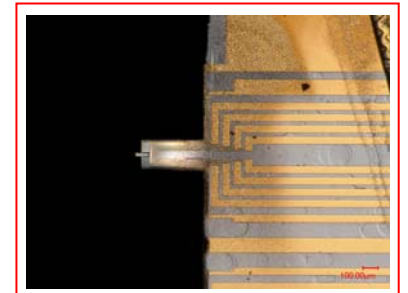
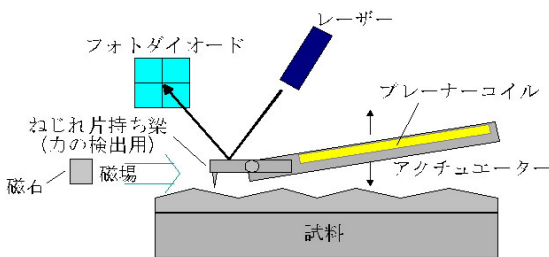
圧電駆動飛行時間質量分析機能付 AFM プローブ

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水晶 AFM プローブ

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